



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Peter de Groot et al. Art Unit : Unknown
Serial No. : 10/795,808 Examiner : Unknown
Filed : March 8, 2004
Title : PROFILING COMPLEX SURFACE STRUCTURES USING SCANNING
INTERFEROMETRY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


INFORMATION DISCLOSURE STATEMENT

Applicant submits the references listed on the attached form PTO-1449.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050, referencing Attorney Docket No. 09712-341001.

Respectfully submitted,

Date: 3/31/04



Marc M. Wefers* for
David L. Feigenbaum
Reg. No. 30,378

Fish & Richardson P.C.
225 Franklin Street
Boston, MA 02110-2804
Telephone: (617) 542-5070
Facsimile: (617) 542-8906

*See attached document certifying that Marc M. Wefers has limited recognition to practice before the U.S. Patent and Trademark Office under 37 C.F.R. § 10.9(b).

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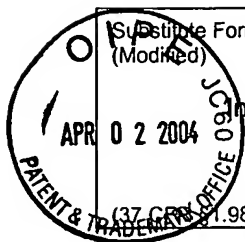
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 U.S. Department of Commerce
Patent and Trademark Office

 Attorney's Docket No.
09712-341001

Application No.

**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

 Applicant
Peter de Groot et al.

 Filing Date
March 8, 2004

Group Art Unit

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,576,479	03/18/1986	Downs	356	351	
	AB	4,999,014	03/12/1991	Gold et al.	356	382	
	AC	5,133,601	07/28/1992	Cohen et al.	356	359	
	AD	5,602,643	02/11/1997	Barrett	356	360	
	AE	6,545,763	04/08/2003	Kim et al.	356	503	
	AF	6,597,460	07/22/2003	Groot et al.	356	512	
	AG						
	AH						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AI	0 397 388 A2	11/14/1990	EPO	G01B	11/06		
	AJ	0 549 166 A2	06/30/1993	EPO	G01B	11/06		
	AK							
	AL							

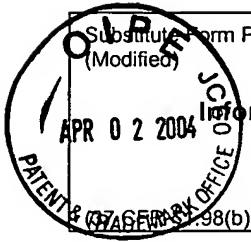
Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AM	Dresel, Thomas et al., "Three-dimensional sensing of rough surfaces by coherence radar", <u>Applied Optics</u> , Vol. 31, No. 7, pp. 919-925 (March 1, 1992)
	AN	Feke, Gilbert D. et al., "Interferometric back focal plane microellipsometry", <u>Applied Optics</u> , Vol. 37, No. 10, pp. 1796-1802 (April 1, 1998)
	AO	Kim, Seung-Woo et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
	AP	Kino, Gordon S. et al., "Mirau correlation microscope", <u>Applied Optics</u> , Vol. 29, No. 26, pp. 3775-3783 (September 10, 1990)
	AQ	Pelligrand, S. et al., "Mesures 3D de topographies et de vibrations a l'echelle (sub)micrometrique par microscopie optique interferometrique", <u>Proc. Club CMOI, Methodes et Techniques Optiques pour l'Industrie</u> (2002)
	AR	Pluta, Maksymilian, "Advanced Light Microscopy", Vol. 3, (Elsevier, Amsterdam, 1993) pp. 265-271
	AS	Rosencwaig, Allan et al., "Beam profile reflectometry: A new technique for dielectric film measurements", <u>Applied Physics Letters</u> , Vol. 60, No. 11, pp. 1301-1303 (March 16, 1992)

Examiner Signature

Date Considered

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Group Art Unit

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	BA	Sandoz, Patrick "Wavelet transform as a processing tool in white-light interferometry", <u>Optics Letters</u> , Vol. 22, No. 14, pp. 1065-1067 (July 15, 1997)
	BB	Shatalin, S.V. et al., "Reflection conoscopy and micro-ellipsometry of isotropic thin film structures", <u>Journal of Microscopy</u> , Vol. 179, Part 3, pp. 241-252 (September, 1995)
	BC	
	BD	

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Date Considered

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